

3/26/04

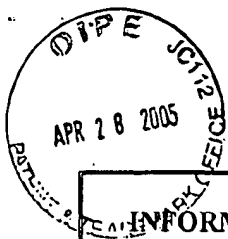
SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811449 Not Yet Assigned			
		APPLICANT Jim Dunphy, et al.					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
Dle	U.S. Pub App No. 2003/0002019	1/2/03	Miller				
	U.S. Pub App No. 2002/0056898	5/16/02	Lopes, et al.				
	U.S. Pub App No. 2002/0063322	5/30/02	Robbins, et al.				
	6,300,294	10/9/01	Robbins, et al.				
	5,694,740	12/9/97	Martin, et al.				
	5,936,758	8/10/99	Fisher, et al.				
	5,610,438	3/11/97	Wallace, et al.				
Dle	5,512,374	4/30/96	Wallace, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
Dle	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247						
	Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13						
	"Optimization of Lubricants fir silica Micromotors" Zarrd, Sensors and Actuators A 46-47 (1995) 598-600						
	"Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233						
	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3						
	"Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE 0-7803-298-5-6, pgs 91-98						
	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269						
	"Stiction reduction processes for surface micromachines" Roya Maboudian Tribology letters 3 (1997) 215-221						
	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353						
	"Measurement of Micromoto Dynamics in Lubricating Fluids" Deng IEEE						
Dle	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147						
EXAMINER			DATE CONSIDERED 6/2/05				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION APR 28 2005 PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449			
		APPLICANT Dunphy, et al.					
		FILING DATE 3/26/04		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
DL	5,939,785	8/17/99	Klonis, et al.				
	5,411,769	8/17/99	Hornbeck				
	6,204,085	3/20/01	Strumpell, et al.				
	2003/0064149	4/3/03	Miller				
	6,259,551	7/10/01	Jacobs				
	5,447,600	9/5/95	Webb				
	6,300,294	10/9/01	Robbins, et al.			 duplicated	
	6,086,726	7/11/00	Renk, et al.				
	6,475,570	11/5/02	Jacobs				
	2004/0100677	5/27/04	Huibers, et al.				
DL	2004/0125346	7/1/04	Huibers				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
DL	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICTION COATINGS FOR MEMS, Pgs 1-6.						
DL	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISITANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.						
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.						
DL	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.						
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.						
DL	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICTION REDUCTION, 1997 IEEE, Pgs. 1399-1402.						
EXAMINER DL				DATE CONSIDERED 6/2005			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 2 OF 2			ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449		
			APPLICANT Dunphy, et al.				
			FILING DATE 3/26/04		GROUP Not Yet Assigned		
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
<i>Dle</i>	2004/0012838	1/22/04	Huibers	<i>1</i>	<i>1</i>		
<i>1</i>	2004/0100594	5/27/04	Huibers, et al.				
	2004/0156090	8/12/04	Patel, et al.				
	5,835,256	11/10/98	Huibers				
	6,046,840	4/4/00	Huibers				
	6,844,959	1/18/05	Huibers, et al.				
<i>Dle</i>	6,867,897	3/15/05	Patel, et al.				
	5,287,096	2/15/94	Thompson, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	<i>1</i>					<input type="checkbox"/>	<input type="checkbox"/>
						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	<i>1</i>						
EXAMINER	<i>Dle</i>			DATE CONSIDERED <i>6/02/05</i>			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line thro